

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of	:	Attorney Docket No. 2005_1890A
Tetsuji TOGAWA et al.	:	<b>Confirmation No. 7353</b>
Serial No. 10/559,135	:	Group Art Unit 3723
Filed February 11, 2008	:	Examiner Eileen P. Morgan
SUBSTRATE POLISHING APPARATUS AND SUBSTRATE POLISHING METHOD	:	<b>Mail Stop: RCE</b>

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**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of June 16, 2009, the period for response having been extended by one month to October 16, 2009, please amend the above-identified U.S. Patent application as follows.